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# IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Lucius M. Sherwin

Docket No.: TI-30661

**TBD** 

Serial No:

TBD

Examiner: TBD

Filed:

08/02/01

Art Unit:

For:

A PARTICLE DETECTION AND REMOVAL APPARATUS FOR USE ON

WAFER FABRICATION EQUIPMENT TO LOWER TOOL RELATED

**DEFECTS FROM PARTICLE CONTAMINATION** 

### PRELIMINARY AMENDMENT

August 2, 2001

**Assistant Commissioner for Patents** 

Washington, DC 20231

Dear Sir:

Please amend the above referenced application as follows:

## In the Specification:

Page 1, before line 1, insert --This application claims priority under 35 USC § 119(e)(1) of provisional application numbers 60/224,434 filed 08/10/00.--

### **REMARKS**

Entry of the foregoing amendment prior to examination is respectfully requested. If the Examiner has any questions or other correspondence regarding this application, Applicant requests that the Examiner contact Applicant's attorney at the below listed telephone number and address.

Respectfully submitted,

Jacqueline J. Garner Attorney for Applicants

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